



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	Baer et al.	)	Group No.:	1763
		)		
Serial No.:	10/675,697	)	Examiner:	Arancibia
		)		
Filed:	09/30/2003	)	Docket No.:	HSJ9-2003-0032US1

For: *"METHOD OF FORMING A READ SENSOR USING PHOTORESIST  
STRUCTURES WITHOUT UNDERCUTS WHICH ARE REMOVED USING  
CHEMICAL-MECHANICAL POLISHING (CMP) LIFT-OFF PROCESSES"*

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

REQUEST FOR RECONSIDERATION

The Applicants respectfully submit this Request for Reconsideration for entry into the present application in response to the Office Action mailed on 05 April 2007.